CLAIMS

What is claimed is:

1	1.	Α	seed layer structure for a nard magnetic material, comprising:
2		a)	at least a first underlayer and a second underlayer located above said first
3			underlayer;
4		b)	at least a first interlayer located between said first underlayer and said second
5			underlayer; and
6		c)	a hard magnetic material located above said second underlayer.
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1		2.	The seed layer structure in claim 1 further comprising a third underlayer and a
2			second interlayer each located above said second underlayer and below said
3			hard magnetic material, wherein said second interlayer is located between said
4			second underlayer and said third underlayer.
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1			3. The seed layer structure in claim 2 further comprising a fourth
2			underlayer and a third interlayer each located above said third
3			underlayer and below said hard magnetic material, wherein said third
4			interlayer is located between said third underlayer and said fourth
5			underlayer.
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1		4.	The seed layer structure in claim 1 further comprising a plurality of alternating
2			underlayers and interlayers each located above said second underlayer and
3			below said hard magnetic material.

1	5.	The seed layer structure in claim 1 wherein said first underlayer and said
2		second underlayer are Cr.
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1	6.	The seed layer structure in claim 1 wherein said first underlayer and said
2		second underlayer are an alloy selected from the group consisting of
3		Cr _X Mo _{1-X} , Cr _X Mn _{1-X} , Cr _X Ti _{1-X} and Cr _X V _{1-X}
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1	7.	The seed layer structure in claim 1 wherein said first interlayer is an oxide.
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1		8. The seed layer structure in claim 7 wherein said oxide is selected from
2		the group consisting of oxides of aluminum, oxides of tantalum, oxides
3		of silicon and oxides of hafnium.
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1	9.	The seed layer structure in claim 1 wherein thickness of said first underlayer
2		and thickness of said second underlayer are each substantially greater than 3
3		nm.
4		
1	10.	The seed layer structure in claim 1 wherein thickness of said first interlayer is
2		substantially between 0.1 nm and 10 nm.
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1	11.	The seed layer structure in claim 1 wherein said hard magnetic material
2		provides longitudinal bias to a ferromagnetic layer in a magnetic sensor.
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1		12. The seed layer structure in claim 11 wherein said magnetic sensor is a
2		giant magnetoresistive sensor.

1			13.	The seed layer structure in claim 11 wherein said magnetic sensor is a	
2				tunnel valve sensor.	
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1			14.	The seed layer structure in claim 11 wherein said magnetic sensor is an	
2				anisotropic magnetoresistive sensor.	
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1			15.	The seed layer structure in claim 11 wherein said magnetic sensor is	
2				selected from the group consisting of top spin valve sensors, bottom	
3				spin valve sensors, giant magnetoresistive sensors, tunnel valve sensors	
4				and anisotropic magnetoresistive sensors.	
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1	16.	A ma	A magnetic sensor for sensing an external magnetic field, comprising:		
2		a)	at lea	ast one ferromagnetic layer with a magnetization responsive to said	
3			exterr	nal magnetic field; and	
4		b)	a long	gitudinal bias structure positioned adjacent to said ferromagnetic layer for	
5			biasin	ng said ferromagnetic layer, said longitudinal bias structure comprising:	
6			1)	at least a first underlayer and a second underlayer located above said	
7			•	first underlayer, wherein said first underlayer and said second	
8				underlayer are selected from the group consisting of Cr, Cr _X Mo _{1-X} ,	
9				Cr_XMn_{1-X} , Cr_XTi_{1-X} and Cr_XV_{1-X} ;	
10			2)	at least a first interlayer located between said first underlayer and said	
11				second underlayer, wherein said first interlayer is selected from the	
12				group consisting of oxides of aluminum, oxides of tantalum, oxides of	
13				silicon and oxides of hafnium; and	
14			3)	a hard magnetic material located above said second underlayer.	

1	17.	The magnetic sensor in claim 16 further comprising a third underlayer and a
2		second interlayer each located above said second underlayer and below said
3	-	hard magnetic material in said longitudinal bias structure, wherein said second
4		interlayer is located between said second underlayer and said third underlayer.
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1 .		18. The magnetic sensor in claim 17 further comprising a fourth underlayer

18. The magnetic sensor in claim 17 further comprising a fourth underlayer and a third interlayer each located above said third underlayer and below said hard magnetic material in said longitudinal bias structure, wherein said third interlayer is located between said third underlayer and said fourth underlayer.

19. The magnetic sensor in claim 16 further comprising a plurality of alternating underlayers and interlayers each located above said second underlayer and below said hard magnetic material in said longitudinal bias structure.

20. The magnetic sensor in claim 16 wherein said magnetic sensor is selected from the group consisting of top spin valve sensors, bottom spin valve sensors, giant magnetoresistive sensors, tunnel valve sensors and anisotropic magnetoresistive sensors.

21. The magnetic sensor in claim 16 wherein thickness of said first underlayer and thickness of said second underlayer are each substantially greater than 3 nm.

22. The magnetic sensor in claim 16 wherein thickness of said first interlayer is substantially between 0.1 nm and 10 nm.

1	23.	A ma	A magnetic read head for sensing an external magnetic field, comprising:		
2		a)	a mag	netic sensor having at least one ferromagnetic layer with a magnetization	
3			respoi	nsive to said external magnetic field; and	
4		b)	a long	gitudinal bias structure positioned adjacent to said ferromagnetic layer for	
5			biasin	g said ferromagnetic layer, said longitudinal bias structure comprising:	
6			1)	at least a first underlayer and a second underlayer located above said	
7				first underlayer, wherein said first underlayer and said second	
8				underlayer are selected from the group consisting of Cr, Cr _X Mo _{1-X} ,	
9				Cr_XMn_{1-X} , Cr_XTi_{1-X} and Cr_XV_{1-X} ;	
10			2)	at least a first interlayer located between said first underlayer and said	
11				second underlayer, wherein said first interlayer is selected from the	
12				group consisting of oxides of aluminum, oxides of tantalum, oxides of	
13				silicon and oxides of hafnium; and	
14			3)	a hard magnetic material located above said second underlayer.	
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1		24.	The m	nagnetic read head in claim 23 further comprising a third underlayer and a	
2		ř.	secon	d interlayer each located above said second underlayer and below said	
3			hard r	nagnetic material in said longitudinal bias structure, wherein said second	
4			interla	ayer is located between said second underlayer and said third underlayer.	
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1			25.	The magnetic read head in claim 24 further comprising a fourth	
2				underlayer and a third interlayer each located above said third	

underlayer and said fourth underlayer.

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underlayer and below said hard magnetic material in said longitudinal

bias structure, wherein said third interlayer is located between said third

26.	The magnetic read head in claim 23 further comprising a plurality of alternating						
	underlayers and interlayers each located above said second underlayer and						
	below said hard magnetic material in said longitudinal bias structure.						

27. The magnetic read head in claim 23 wherein said magnetic sensor is selected from the group consisting of top spin valve sensors, bottom spin valve sensors, giant magnetoresistive sensors, tunnel valve sensors and anisotropic magnetoresistive sensors.

28. The magnetic read head in claim 23 wherein thickness of said first underlayer and thickness of said second underlayer in said longitudinal bias structure are each substantially greater than 3 nm.

29. The magnetic read head in claim 23 wherein thickness of said first interlayer in said longitudinal bias structure is substantially between 0.1 nm and 10 nm.